



PATENT  
Attorney Docket No. 02887.0257-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	)	
Akira HAMAGUCHI <i>et. al.</i>	)	Group Art Unit: 2624
	)	
Application No.: 10/687,828	)	Examiner: Vikkram BALI
	)	
Filed: October 20, 2003	)	Confirmation No.: 2967
	)	
For: METHOD AND APPARATUS FOR	)	
DETERMINING DEFECT	)	
DETECTION SENSITIVITY DATA,	)	
CONTROL METHOD OF DEFECT	)	
DETECTION APPARATUS, AND	)	
METHOD AND APPARATUS FOR	)	
DETECTING DEFECT OF	)	
SEMICONDUCTOR DEVICES	)	

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**REPLY TO OFFICE ACTION**

In reply to the Office Action mailed January 25, 2007, the period for response having been extended to July 25, 2007 by a request for extension of three months and fee payment filed concurrently herewith, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks/Arguments** follow the amendment sections of this paper.